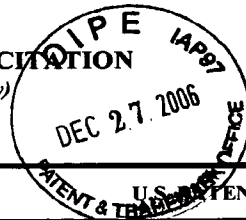


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Applicant(s)

Mineo HIRAMATSU, et al.

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Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		2001-081570	03/27/2001	JAPAN			ABS	
		11-067490	03/09/1999	JAPAN			ABS	
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"Formation of Vertically Aligned Carbon Nanotubes by Dual-RF-Plasma Chemical Vapor Disposition", by Takashi HIRAO, et al.

EXAMINER

/Mandy Louie/

DATE CONSIDERED

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